

Collaboration on Development of Sapphire for Test Masses

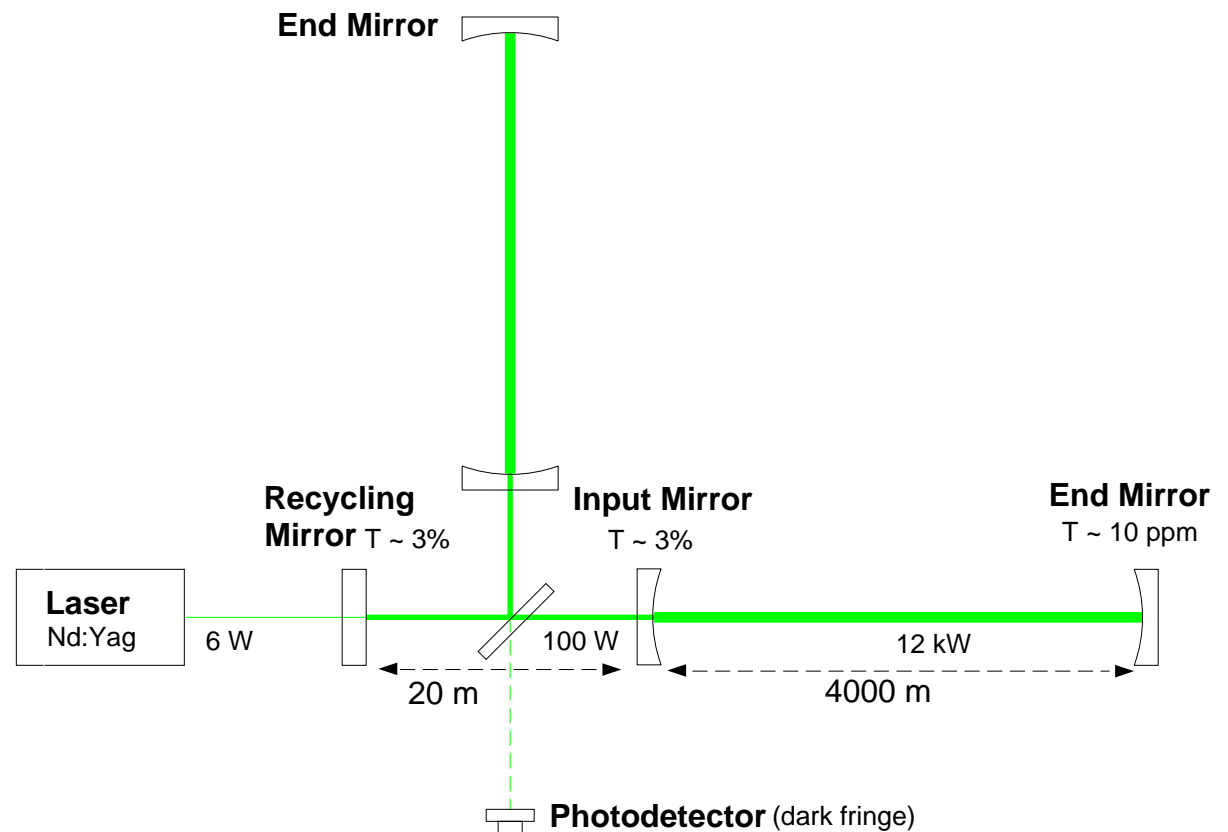
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Large Optical Components ("Core Optics")

- Test Masses
 - ›› End Mirror
 - ›› Input Mirror
- Beamsplitter
- Recycling Mirror
- Initial LIGO substrates will all be fused silica
- Future LIGO substrates????



Issues for Choosing a Test Mass Material

- Optical surface quality (LIGO, ACIGA, Industry)
 - ›› Low spatial frequency surface figure errors, leading to small angle scattering
 - ›› Microroughness
- Optical homogeneity and birefringence (ACIGA, Virgo, LIGO)
 - ›› For transmissive applications
- Thermal distortion and lensing (Virgo, Stanford, LIGO)
 - ›› Bulk Absorption
 - ›› Thermal Conductivity
- Thermal noise (ACIGA, Virgo, LIGO)
 - ›› High mechanical Q to minimize thermal noise ($Q \sim 10^6$ - 10^8)
 - ›› Size, density, speed of sound,...
- Producibility and cost (LIGO, Crystal Systems, SIOM)



Thermal Noise

- The primary motivation for sapphire test masses is thermal noise
- Thermal noise

$$\Delta x^2 = \frac{4kT}{\omega} \cdot \frac{\Phi(\omega)}{M\omega_0^2}$$

›› Loss factor Φ for sapphire ~ 0.1 that for fused silica

›› Sapphire is denser than fused silica ($\sim x2$) and has higher speed of sound so $M\omega_0^2$ is larger by $x6$

- Net gain is nearly $x10$ in internal thermal noise
- (Provided suspension does not compromise internal Q)
- Near-term tests of Q's at UWA(ACIGA), eventually at Virgo/LIGO



Microroughness

- Largest source of lost optical power in initial detectors
- Sapphire is an exceptionally hard material
 - ›› Moh hardness 9 (vs. ~6 for fused silica); harder than most polishing powders
- Microroughness $< 1 \text{ \AA}$ demonstrated 10 years ago
 - ›› **But** never on the scale of LIGO optics
- For simple “smooth” surfaces,

$$\text{Scatter Loss} = \left(4\pi\frac{\sigma}{\lambda}\right)^2$$

- ›› For $\lambda = 1.063\mu\text{m}$, $\sigma = 0.2\text{nm}$, scatter loss $\sim 6 \text{ ppm}$
- Point defects likely to be an issue due to use of diamond dust
 - ›› Point defects will cause few ppb loss each
- **CSIRO and GO pieces to be tested by LIGO**



Coating Issues

- Main coating issue: Stress
 - ›› Thermal expansion coefficient of sapphire ~ 15 x that of fused silica
 - ›› Expansion coefficient has different values parallel and perpendicular to crystal axis
- Anisotropy in expansion will lead to birefringence in mirror, i.e., cavity will have different resonance point for different polarizations
 - ›› Observed in cryogenic (?) cavity at UWA at 0.1 milliradian level
 - ›› Leads to requirement that even ETM's should have crystal axis normal to mirror surface
- Discussions with REO indicate willingness to work with LIGO on development and no particular concerns about coating sapphire



Optical Homogeneity

- Higher index of refraction for Sapphire means that equal $\delta n/n$ gives factor of 2 larger OPD
- Limited number of measurements have given as good as $\delta n = 3 \times 10^{-6}$
 - ›› May be measurement limited....
 - ›› Compare fused silica 2.5×10^{-7}
- Technology for control of optical homogeneity not yet well developed
- Working with Crystal Systems and Shanghai Institute of Optics and Fine Mechanics (SIOM) to evaluate current capabilities



Heating Effects

- Surface distortion
 - ›› Important for reflective and transmissive optics
 - ›› Typically not most important in SiO_2 due to low expansion coefficient
- Thermal lensing
 - ›› Important for transmissive optics only
 - ›› Important in SiO_2 due to low thermal conductivity and high dn/dT
- Heat deposition matches beam profile; temperature gradient from heat flow to optic surfaces (radiatively coupled to vacuum chamber)
 - ›› First order distortion is a simple change in radius (or simple lens)
 - ›› Gaussian beam profile leads to higher order distortions



Absorption in Sapphire

- Source of absorption unknown; some speculation due to Ti^{3+} (Stanford data show some correlation with fluorescence)

| Sample | <i>Blair et al. Published Measurements</i> | <i>Absorption-Stanford Measurement</i> | <i>Absorption-Virgo Measurement</i> |
|----------------------|---|---|--|
| Union Carbide (1996) | 16 - 22 ppm/cm | -- | -- |
| CSI Hemex Ultra | 55 +- 4 | 140 | -- |
| RISC, China | 200 +- 20 | -- | -- |
| Melles-Griot | 11 - 16 | -- | -- |
| CSI White | 3.1 - 3.5 | 120 | -- |
| CSI White #0 (1998) | -- | 41 (recal underway) | -- |
| CSI White #1 (1998) | -- | 68 (recal underway) | 142 +- 15 |
| CSI White #2 (1998) | -- | 58 (recal underway) | 90 +- 10 |

- Typical SiO_2 values 2-20 ppm/cm at 1.064 μm
 - ›› IR absorption due to OH (usually?)



Surface Distortion

- Reflective optics
 - ›› Proportional to absorption (of coating)
 - ›› Inversely proportional to thermal conductivity of substrate
 - ›› Proportional to coefficient of thermal expansion
- Compare sapphire with fused silica

| <i>Property</i> | <i>Fused Silica</i> | <i>Sapphire</i> |
|----------------------------------|---------------------------------------|--------------------------------------|
| Thermal Conductivity | 1.4 W m ⁻¹ K ⁻¹ | 30 W m ⁻¹ K ⁻¹ |
| Coefficient of Thermal Expansion | 5 x 10 ⁻⁷ K ⁻¹ | 8 x 10 ⁻⁶ K ⁻¹ |
| Relative Surface Distortion | 1 | ~0.7 |



Thermal Lensing

- Important for transmissive optics only
 - ›› Proportional to absorption
 - ›› Inversely proportional to thermal conductivity of substrate
 - ›› Proportional to dn/dT
- Compare sapphire with fused silica

| <i>Property</i> | <i>Fused Silica</i> | <i>Sapphire</i> |
|--------------------------|---------------------------------------|--------------------------------------|
| Absorption | 4 ppm/cm | 10 ppm/cm (????) |
| Thermal Conductivity | $1.4 \text{ W m}^{-1} \text{ K}^{-1}$ | $30 \text{ W m}^{-1} \text{ K}^{-1}$ |
| dn/dT | $9 \times 10^{-6} \text{ K}^{-1}$ | $13 \times 10^{-6} \text{ K}^{-1}$ |
| Relative Thermal Lensing | 1 | ~ 0.15 (????) |



Production Capacity

- Sapphire boules up to 65 kg have been produced in test runs
- Standard production sizes up to 32 cm dia x 15 cm (~30 kg)
 - ›› **But** not (yet?) with C axis parallel to cylinder axis
- Largest C-axis pieces currently 15 cm dia x 15 cm
- Growth cycle for large boules is 1-2 months
 - ›› Production of substrates for ETM's alone would take ~1 year of a dedicated furnace once process is finalized
- Polishing cycle is also slow (example: single 15 cm piece at GO quoted at 6-8 month delivery time)
- Good news: Production costs approximately comparable with Heraeus fused silica
- **LIGO working with Crystal Systems and SIOM**



Future Directions

- Production Issues

- ›› Size is biggest challenge, **but** ability to produce sufficient number is still iffy

- Polishing

- ›› Need to determine ability to achieve adequate surface figure

- Understand limits to Q (fundamental limit or technical limit)

- ›› Including how to suspend and control without degrading intrinsic Q

- Issues specific to ITM's

- ›› Source of absorption and its control

- ›› Birefringence, homogeneity,

